**Cleanroom Project Proposal Form**

1. **Outline of procedure for managing access:**
   1. External enquiry:
   2. Initial request to Cleanroom Manager and further discussion, if required.
   3. Submit proposal form. Send to [UOB-nanofab@bristol.ac.uk](mailto:UOB-nanofab@bristol.ac.uk)
   4. Proposal assessment by Cleanroom Management Committee, if required.
   5. Finalise process requirement and estimation of costs.
   6. Cleanroom Manager to arrange contract.
   7. Purchase order raised.
   8. Honorary Associate request form submission (required to work in Cleanroom).
   9. Process work commences:
      1. Cleanroom induction and tool training, if required.
      2. Alternatively, work carried out by UoB staff.
   10. Internal enquiry
       1. Initial request to Cleanroom Manager and further discussion, if required.
       2. Submit proposal form. Send to [UOB-nanofab@bristol.ac.uk](mailto:UOB-nanofab@bristol.ac.uk)
       3. Proposal assessment by Cleanroom Management Committee, if required.
       4. Complete online ‘Cleanroom Access Request Form’.
       5. Wait for approval.
       6. Complete Cleanroom Induction. Receive training and complete risk assessment process for tools and procedures.
2. **Cleanroom Equipment Costs**

For internal users, cleanroom usage is charged by applying tiered equipment hourly rates. There are four tiers with equipment grouped according to the table below. Please refer to the fEC calculator for the charging rates as these are subject to change. External users can contact the Cleanroom Manager for the rates associated with individual tools.

|  |  |  |  |
| --- | --- | --- | --- |
| **Cleanroom Tier 1** | **Cleanroom Tier 2** | **Cleanroom Tier 3** | **NSQI Cleanroom** |
| Bench fee | AFM | ICP 1 (III/V, II/VI) | Nanoscribe |
| Plasma asher | Dektak XT Profilometer | ICP 2 (Si) | Voyager EBL |
| Evaporator | Dicer | PECVD |  |
| HF | Ellipsometer |  |  |
| Hotplate | Heidelberg laser writer |  |  |
| Microscope | Mask Align 1 (Suss) |  |  |
| Mini sputter (SEM) | Mask Align 2 (Midas) |  |  |
| Oven | Optical profilometer |  |  |
| PDMS moulding | RIE 1 (JLS oxide/nitride) |  |  |
| Probe station | RIE 2 (JLS) |  |  |
| Scribing | RIE 3 (old oxide/nitride) |  |  |
| Solvent bench | RTP |  |  |
| Spin coater | Zeiss SEM/EBL |  |  |
| Wet bench | Sputter/ebeam evap |  | QuPIC tools |
|  | Wirebond |  | BrisSynBio tools |

1. **Cleanroom Project Proposal**

**Section 1. Project information.**

|  |  |
| --- | --- |
| New Project | Yes  No |
| If no, insert previous project title and/or ID: |  |
| If yes, insert project title: |  |
| Estimated available budget: |  |

**Section 2. Applicant details.**

|  |  |  |  |
| --- | --- | --- | --- |
| PI Name: |  | Faculty: |  |
| Email: |  | School/dept: |  |
|  | | | |
| **Cleanroom User details:** | | | |
| 1. Name: |  | Position: |  |
| 1. Name: |  | Position: |  |
| 1. Name: |  | Position: |  |
| 1. Name: |  | Position: |  |
| **External applicants only:** | | | |
| Company name: |  | | |
| Address: |  | | |
|  |  | | |
|  |  | Postcode: |  |

**Section 3. Technical description.**

|  |  |
| --- | --- |
| Overall goal | *Brief description of research goals of project* |
|  | |
| Cleanroom requirement | *Brief explanation of the work required in the cleanroom, reference any relevant papers* |
|  | |

**Section 4. Cleanroom details.**

|  |  |  |  |  |  |
| --- | --- | --- | --- | --- | --- |
| Assets required: | | | | | |
| **Tier 1:** |  | **Tier 2:** |  | **Tier 3:** |  |
| Bench |  | AFM |  | ICP 1 (III/V, II/VI) |  |
| Plasma asher |  | Dektak XT Profilometer |  | ICP 2 (Si) |  |
| Evaporator |  | Dicer |  | PECVD |  |
| HF |  | Ellipsometer |  |  |  |
| Hotplate |  | Heidelberg laser writer |  |  |  |
| Microscope |  | Mask Align 1 |  |  |  |
| Mini sputter (SEM) |  | Mask Align 2 |  | **NSQI:** |  |
| Oven |  | Optical profilometer |  | Nanoscribe |  |
| PDMS moulding |  | RIE 1 (JLS oxide/nitride) |  | Voyager EBL |  |
| Probe |  | RIE 2 (JLS) |  |  |  |
| Scribing |  | RIE 3 (old oxide/nitride) |  | **Cleanroom Staff:** |  |
| Solvent bench |  | RTP |  | Process Engineer |  |
| Spin coater |  | Zeiss SEM/EBL |  |  |  |
| Wet bench |  | Sputter/ebeam evap |  |  |  |
|  |  | Wirebond |  |  |  |
|  |  |  |  |  |  |

|  |  |  |
| --- | --- | --- |
| Standard processes required: | |  |
|  | | |
| Other processes required: | |  |
|  | | |
| Consumables required: |  | |
|  | | |

**Section 5. Reporting and acknowledgements.**

It is a condition of usage that all publications and presentations describing work that has been supported by the Cleanroom Facility should contain an acknowledgement of the Cleanroom Facility. It is also a requirement for the Cleanroom Manager to be notified of any publications or presentations. Recommended text is below:

*‘This work was supported by the University of Bristol Cleanroom Facility’*

Where grants have been used to purchase equipment for the cleanroom that has subsequently been used for research not associated with the original grant a further acknowledgment should be included. The equipment to which this applies is labelled. Recommended text is below:

QuPIC equipment: *‘This work was supported by the UK EPSRC grant QuPIC (EP/N015126/1).’*

BrisSynBio equipment: *‘This work was supported by BrisSynBio, a BBSRC/EPSRC Synthetic Biology Research Centre, Grant No. BB/L01386X/1.’*

When appropriate, it would be appreciated if any successes or awards relating to research conducted in the cleanroom be forwarded to the Cleanroom Manager.

**Section 6. Declaration.**

The PI must sign this document and, in submitting this application, agrees to the following:

* To include the acknowledgements as outlined above in any publication or presentation that includes results obtained from work carried out in the Cleanroom Facility.
* To provide a list of all papers, presentations and accomplishments associated with results obtained from work carried out in the Cleanroom Facility.

|  |  |
| --- | --- |
| Signature | Date |
| Check box in lieu of signature if submitting document electronically: |  |